

Supplementary Materials

Plasma-Etched Vertically Aligned CNTs with Enhanced Antibacterial Power

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Table S1. Optimization of plasma treatment conditions.

Identifier	Ar [sccm]	O ₂ [sccm]	Pressure [mTorr]	Power [W]	Time [min]
1	0	195	1	33	1
2	0	66	40	100	1
3	0	66	40	100	2
4	52	14	40	80	1
5	52	14	40	80	5
6	20	5	70	50	5
7	20	5	100	50	5
8	10	2	200	50	5
9	10	2	200	35	5

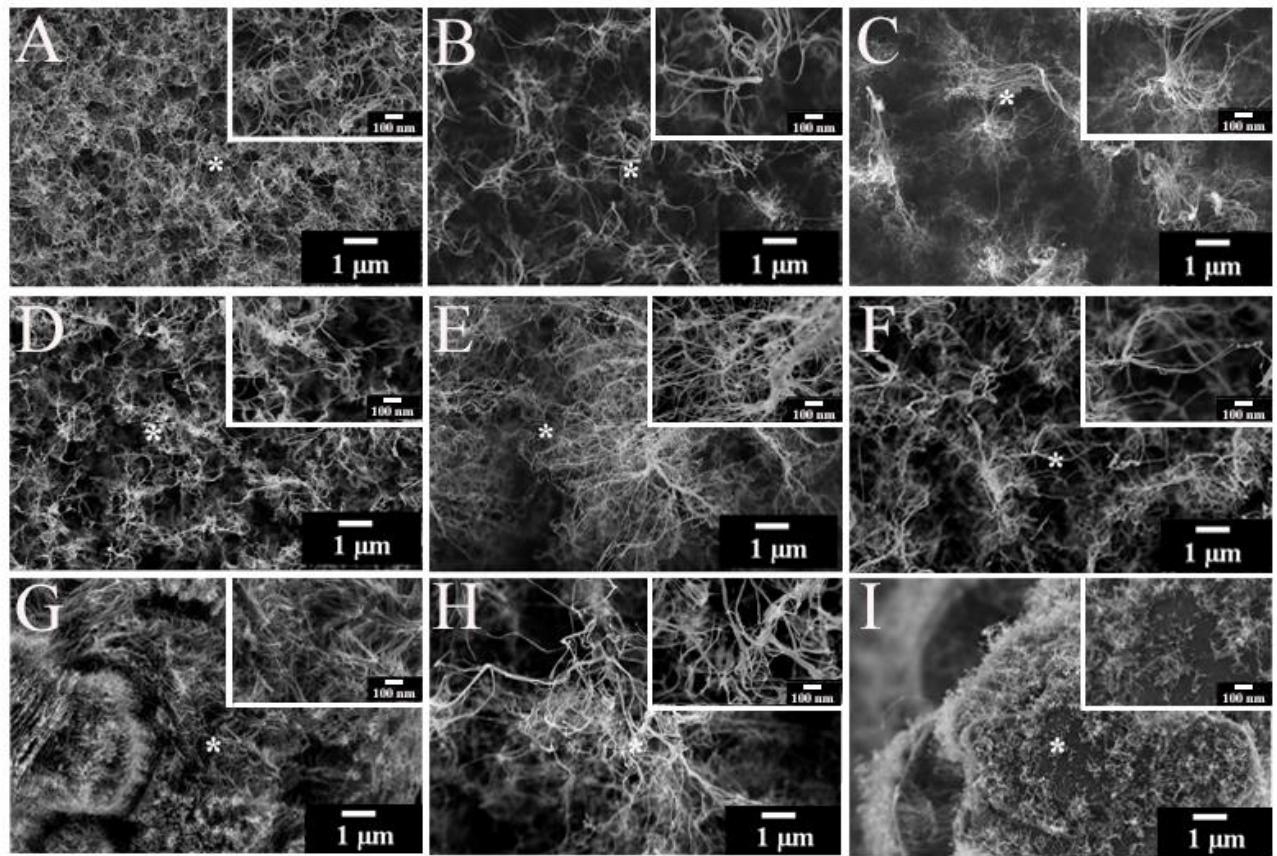


Figure S1. (A-I) Top view SEM micrographs of VA-CNTs modified with different plasma etching conditions showing the morphology of: (A) sample 1 in Table S1 where no significant morphological alterations occur and the crust layer seems to be still present over the surface of CNT mats (*i.e.* “light” etching), (B-C) samples identified as 2 and 3 in Table S1 in which the uniform layer of randomly oriented CNTs (*i.e.* crust layer) switches to a more spiky CNTs arrangement, categorized as “aggressive” etching, (D-H) samples 4-8, upon which significant morphological and structural alterations emerge, (I) sample 9 where the crust is removed and the structural integrity of CNT forests is maintained, identified as “modest” etching.